

## Electronic Supplementary Information (ESI) for:

### **Frequency-dependent stimulated and post-stimulated voltage control of magnetism in transition metal nitrides: towards brain-inspired magneto-ionics**

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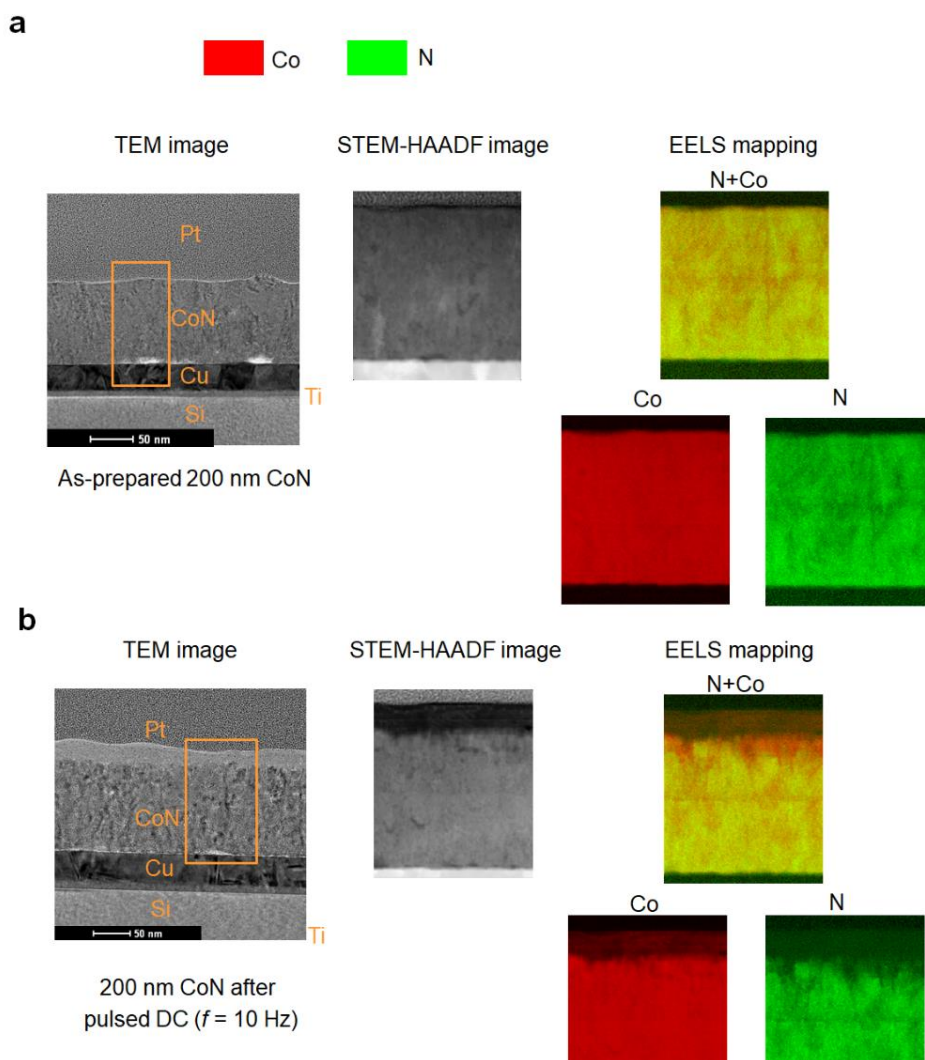
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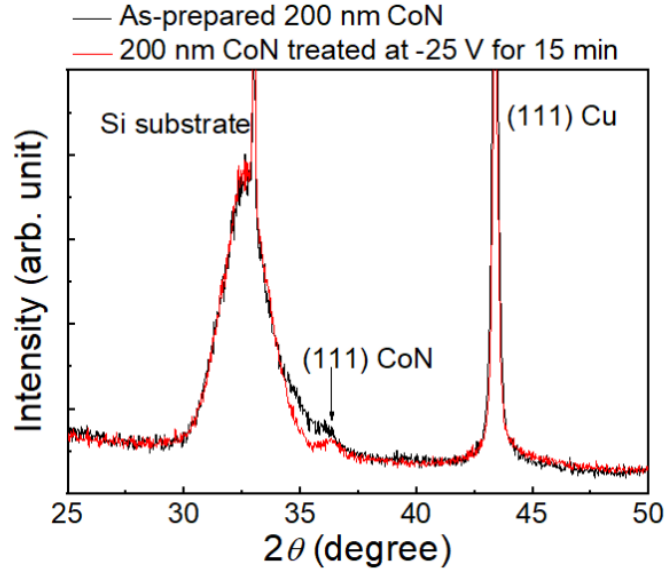
### **Compositional and structural characterization**

High-angle annular dark-field scanning transmission electron microscopy (HAADF-STEM) and electron energy loss spectroscopy (EELS) were performed along the cross-sections of as-prepared 200 nm-thick CoN films and a 200 nm-thick CoN film electrolyte-gated at -25 V for 10 min. As shown in Fig. S1a and b, the as-prepared 200 nm-thick CoN films show a highly nanostructured morphology with homogeneous composition. As shown in Fig. S1b, upon gating at -25 V for 10 min, a well-defined interface between a N-free and highly porous Co top layer and the rest of unaltered CoN film can be observed both in the HAADF-STEM image and the EELS mappings, evidencing the existence of a planar N migration front in agreement with previous results<sup>11</sup>.

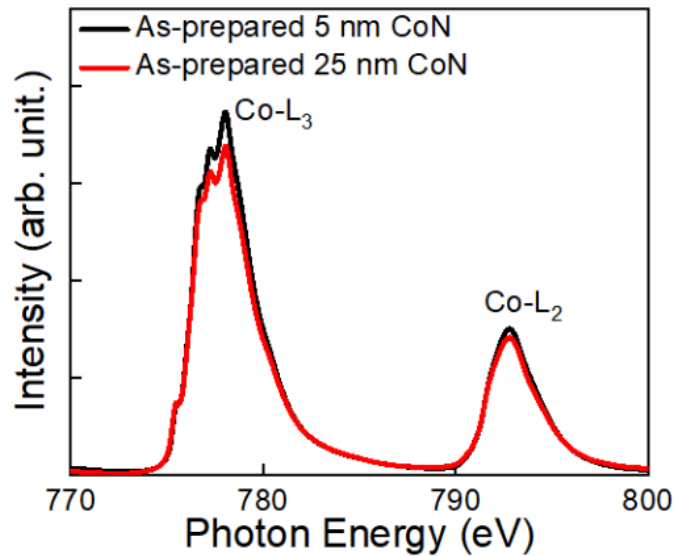
As seen in Fig. S2, the  $\theta/2\theta$  X-ray diffraction (XRD) pattern of an as-prepared 200 nm-thick CoN film reveals the presence of the (111) peak of CoN, indicating the growth of a textured phase. Upon subjecting a 200 nm-thick CoN film at -25 V for 15 min, the intensity of the (111) peak of CoN significantly decreases, in agreement with the denitriding caused but the transport of N ions towards the electrolyte.



**Fig. S1.** Compositional characterization by high-angle annular dark-field scanning transmission electron microscopy (HAADF-STEM) and electron energy loss spectroscopy (EELS), and structural characterization by transmission electron microscopy (TEM). (a) TEM image of an as-prepared 200 nm-thick CoN film together with the HAADF-STEM image and corresponding Co and N EELS mappings of the area marked with a rectangle. (b) TEM image of a 200 nm-thick CoN film subjected to a -25 V for 600 s together with the HAADF-STEM image and corresponding Co and N EELS mappings of the area marked with a rectangle.



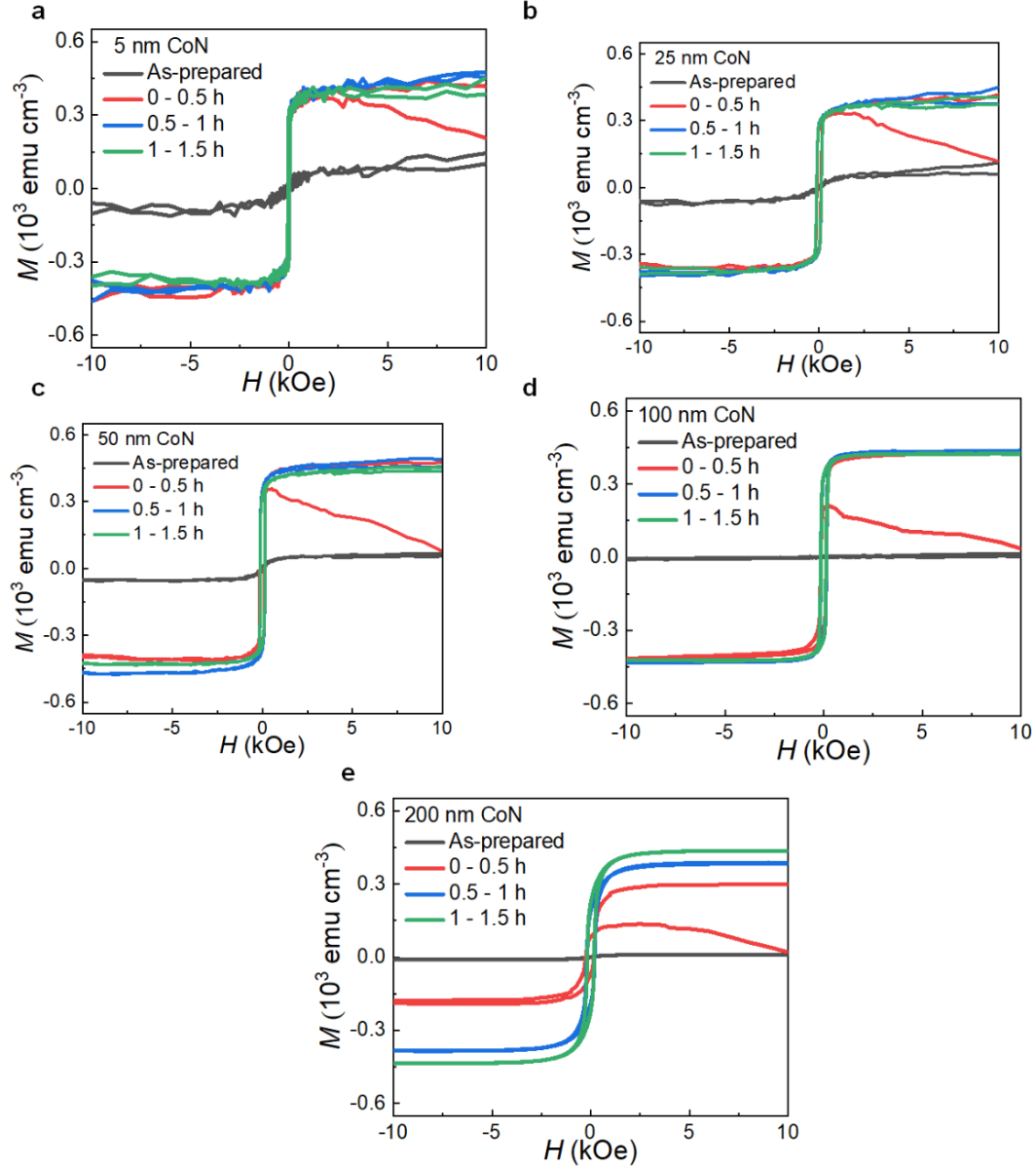
**Fig. S2.** Structural characterization by X-ray diffraction (XRD).  $\theta/2\theta$  XRD diffraction patterns of an as-prepared 200 nm-thick CoN film and a 200 nm-thick CoN film after being treated at -25V for 15 min. For phase identification, the cards no. ICDD JCPDF 00-001-1241 and ICDD JCPDF 00-016-0116, were used for Cu and CoN, respectively.



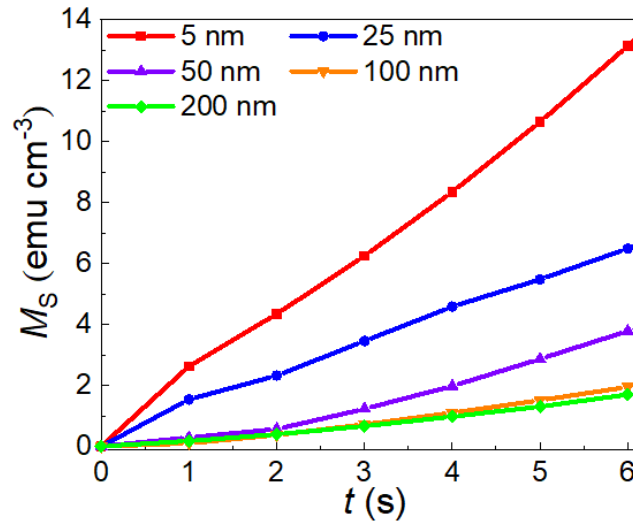
**Fig. S3.** Compositional characterization by X-ray absorption spectroscopy. Co L<sub>2,3</sub>-edge X-ray absorption spectroscopy measurements of the 5 nm- and 25 nm-thick CoN films.

### Magneto-ionic characterization

Fig. S4 shows the hysteresis loops of CoN films with thickness ranging from 5 to 200 nm, sequentially recorded while electrolyte-gated at  $-25$  V until reaching a stable state. The as-prepared CoN-based heterostructures exhibit some traces of ferromagnetic signal ( $< 10 \text{ emu cm}^{-3}$ ), which could be ascribed to local deviations of CoN stoichiometry at the Cu-CoN interface.



**Fig. S4.** Consecutive in-plane VSM hysteresis loops (each lasting 30 min) of the as-prepared film (black) and the films biased under  $-25$  V: **a**, 5 nm, **b**, 25 nm, **c**, 50 nm, **d**, 100 nm, and **e**, 200 nm CoN films.



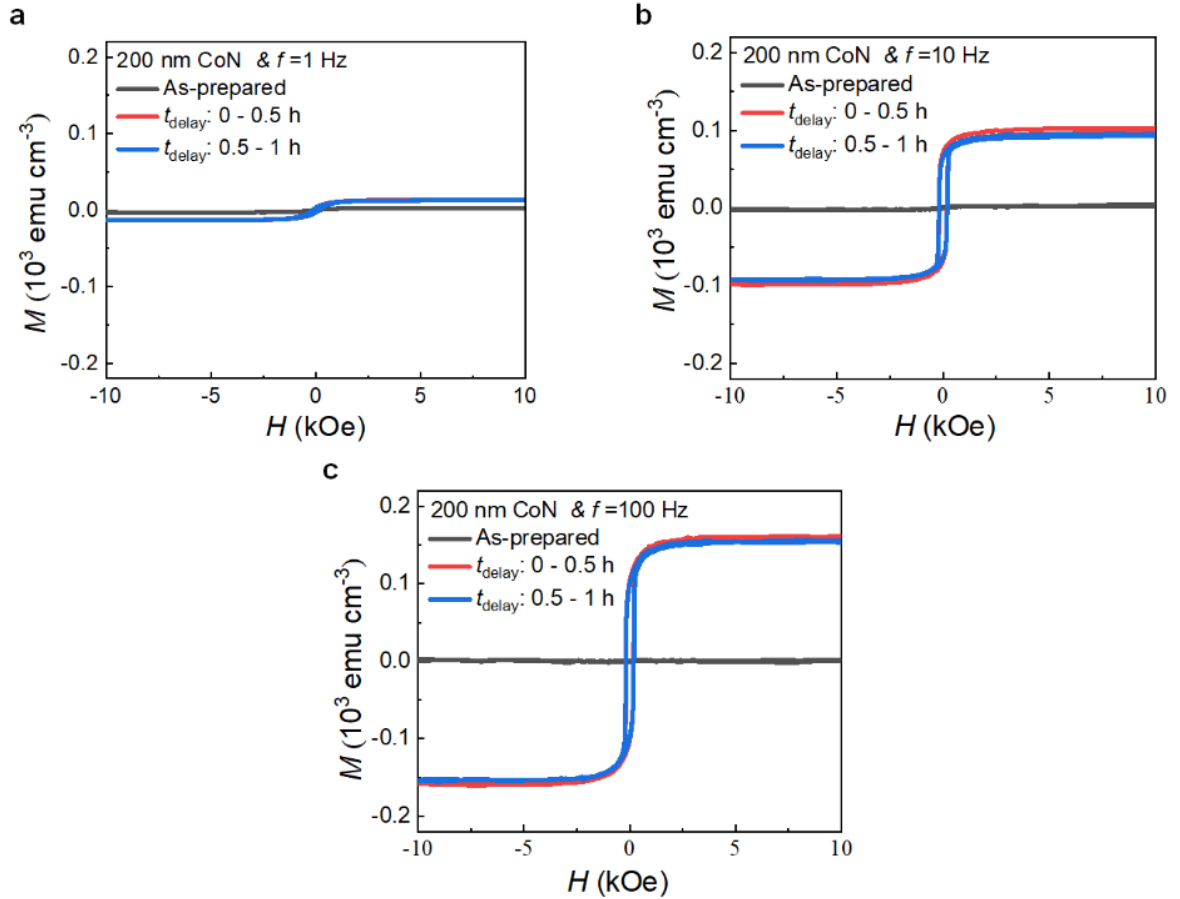
**Fig. S5.** Zoom of Fig. 1c in initial stages to highlight the generation of magnetization. Saturation magnetization ( $M_s$ ) as a function of time  $t$  from 0 to 6 s for a CoN films with thickness ranging from 5 to 200 nm under electrolyte-gating at -25 V while applying an external in-plane magnetic field of 10 kOe.

**Table S1.** Thickness-dependent magnetic and magnetoelectric parameters obtained from the consecutive hysteresis loops presented in Fig. S4 and  $M_s$  vs.  $t$  plots of Fig. S5.

Thickness (nm)	$\Delta M$ ( $H = 10$ kOe) (emu cm <sup>-3</sup> ) upon -25 V for 1 s	$\Delta M$ ( $H = 10$ kOe) (10 <sup>3</sup> emu cm <sup>-3</sup> ) upon -25 V for 50 s	$\Delta M$ ( $H = 10$ kOe) (10 <sup>3</sup> emu cm <sup>-3</sup> ) upon saturation [minimum time required to reach a stable $M_s$ ]	$H_c$ (Oe)
5	2.6	0.235	0.297 [60 s]	35
25	1.5	0.132	0.305 [130 s]	132
50	0.3	0.068	0.379 [< 1 h]	132
100	0.1	0.040	0.423 [< 1 h]	143
200	0.1	0.037	0.507 [12 h]	179

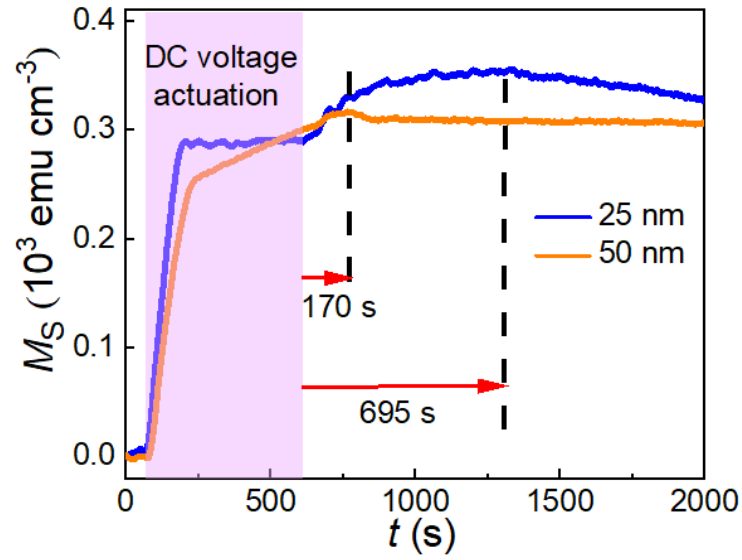
**Table S2.**  $M_S$  attained once magneto-ionic process saturates (*i.e.*, maximum value), normalized by the time required to reach it ( $\Delta t$ ) and by the absolute value of the applied voltage ( $|\Delta V|$ ), from the current results and previous related works from the literature<sup>3,11-14,17</sup>

Film	85 nm-thick Co <sub>3</sub> O <sub>4</sub> film	85 nm-thick CoN film	85 nm-thick FeN film	5 nm-thick Co <sub>3</sub> O <sub>4</sub> film	30 nm-thick CoMnN film	5 nm-thick CoN film (current work)
$M_S/(\Delta t \Delta V )$ (emu cm <sup>-3</sup> h <sup>-1</sup> V <sup>-1</sup> )	7.8	52.0	7.2	32.0	64.5	432.0



**Fig. S6.** In-plane vibrating sample magnetometry hysteresis loops (each lasting 30 min) of an as-prepared 200 nm CoN thin film and a 200 nm CoN film subjected to pulsed DC voltage

actuation for 0.5 and 1h at a frequency of (a) 1 Hz, (b) 10 Hz and (c) 100 Hz. Note that  $t_{\text{delay}}$  refers to the time after the voltage has been switched off.



**Fig. S7.** Time evolution of the saturation magnetization ( $M_S$  vs.  $t$ ) during and after DC voltage actuation at -25V for 20 nm and 50 nm thick CoN films. Dashed lines mark the start of magnetization turning point.